



RON NAFTALI

*Chief Technology Officer
Process Diagnostics and Control*

Ron Naftali is chief technology officer for Process Diagnostics and Control at Applied Materials, Inc. In this role, he continues to develop innovative technical product solutions to address our customers' biggest challenges in inspection and metrology.

Mr. Naftali has more than 17 years of experience in PDC and wafer inspection at Applied and has been instrumental to the company's technical leadership. He was the lead technologist and architect behind many successful products including the UVision® and Compass®/ComPLUS families. Together, these product lines have generated more than \$1 billion in revenue. He is an exceptional technologist with a vast range of technical capabilities who also has extensive knowledge of the end applications enabled by Applied's tools. His expertise spans physics, optics, electronics and motion, image processing and embedded computation.

Mr. Naftali holds 58 active patents and patent applications worldwide, including 29 U.S. patents. He holds a bachelor of science degree with honors in electrical engineering, a bachelor of arts degree in physics and a master of science degree in electrical engineering from the Technion-Israel Institute of Technology.
